

TSMC-01-1037



December 10, 2003

To: Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
28 Davis Avenue
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/661,793 09/12/03 |

Chi-An Kao et al.

CONSTANT AND REDUCIBLE HOLE BOTTOM
CD IN VARIABLE POST-CMP THICKNESS
AND AFTER-DEVELOPMENT-INSPECTION CD
| _____ |

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.

The following Patents and/or Publications are submitted to
comply with the duty of disclosure under CFR 1.97-1.99 and
37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
deposited with the United States Postal Service as first class
mail in an envelope addressed to: Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450, on December 19, 2003.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

SB Ackerman 12/19/03

U.S. Patent 5,926,690 to Toprac et al., "Run-to-run control Process for Controlling Critical Dimensions," discloses run-to-run control process for controlling Critical Dimension.

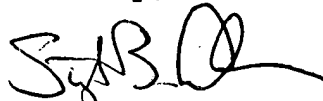
U.S. Patent 6,225,134 to Meisner, "Method of Controlling Linewidth in Photolithography Suitable for Use in Fabricating Integrated Circuits," teaches a method for linewidth control.

U.S. Patent 6,309,976 to Lin et al., "Critical Dimension Controlled Method of Plasma Descum for Conventional Quarter Micron and Smaller Dimension Binary Mask Manufacture," discloses a CD control method including an After Development Inspection (ADI).

U.S. Patent 6,235,440 to Tao et al., "Method to Control Gate CD," discloses a gate CD control method including an ADI.

U.S. Patent 6,161,054 to Rosenthal et al., "Cell Control Method and Apparatus," teaches a cell control method.

Sincerely,

A handwritten signature in black ink, appearing to read "S.B. Ackerman", with a stylized flourish at the end.

Stephen B. Ackerman,
Reg. No. 37761

Form PTO-1449

Document Number (Optional)

Application Number

TSMC-01-1037

10/661,793

Applicant

Chi-An Kao et al.

Filing Date

09/12/03

Group Art Unit

INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

U. S. PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
5926690	7/20/99	Toprac et al.	438	17	5/28/97
6225134	5/1/01	Meisner	438	7	10/30/98
6309976	10/30/01	Lin et al.	438	706	3/22/99
6235440	5/22/01	Tao et al.	430	30	11/12/99
6161054	12/12/00	Rosenthal et al.	700	121	9/17/98

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation
					YES NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.